



CERTIFICATE OF MAILING

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Kristi L. Davidson, Reg. No. 44,643

8/9/05

Date

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Serial No.:

10/797,876

Filed:

March 10, 2004

Group Art Unit:

2813

Examiner:

Jennifer M. Dolan Anthony Dip et al.

Applicant: Title:

SILICON GERMANIUM SURFACE LAYER FOR HIGH-K

DIELECTRIC INTEGRATION

Attorney Docket:

TPS-007

Confirmation No.:

5070

Cincinnati, Ohio 45202

August 9, 2005

Mail Stop Amendment Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Sir:

SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

In accordance with the duty of candor and good faith imposed by 37 C.F.R. §1.56, and means of complying therewith according to 37 C.F.R. §\$1.97 and 1.98, the references listed on the attached Form PTO-1449 are called to the attention of the United States Patent and Trademark

Application Serial No. 10/797,876 Supplemental Information Disclosure Statement submitted August 9, 2005 from International Search Report of PCT/US2005/000661

Office in connection with the above-identified patent application. Because the requirement (37 C.F.R. §1.98(a)(2)(i)) for submitting copies of U.S. patents and published applications has been waived, copies of only the foreign cited references and/or other documents are enclosed herewith. Applicants have also enclosed a copy of the foreign Search Report listing these references. It is noted that U.S. Patent Publication No. US 2001/0055888 A1 has now issued as U.S. Patent No. 6,488,777, and therefore is referenced as such on the Form PTO-1449.

It is submitted that the cited references do not disclose or render obvious the subject matter claimed in the present application.

Certifications under 37 C.F.R. § 1.97(e) and § 1.704(d)

Each item of information contained in the information disclosure statement was first cited in a communication from a foreign patent office in a counterpart foreign application not more than three months prior to the filing of the information disclosure statement.

Each item of information contained in the information disclosure statement was cited in a communication from a foreign patent office in a counterpart application and to the knowledge of the person signing the certification after making reasonable inquiry, no item of information contained in the information disclosure statement was known to any individual designated in 37 C.F.R. § 1.56(c) more than thirty days prior to the filing of the information disclosure statement.

Application Serial No. 10/797,876 Supplemental Information Disclosure Statement submitted August 9, 2005 from International Search Report of PCT/US2005/000661

Applicants do not believe that any fees are due in connection with this submission. However, if such petition is due or any fees are necessary, the Commissioner may consider this to be a request for such and charge any necessary fees to Deposit Account No. 23-3000.

Respectfully submitted,

WOOD, HERRON & EVANS, L.L.P.

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Sheet 2 (B) of 2

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INFORMATION DISCLOSURE STATEMENT BY APPLICANT														APPLICANT Anthony Dip et al.								
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